

Claims

- 1 1. A structure comprising:
- 2 a first substrate and a second substrate; and
- 3 first solder bumps and second solder bumps
- 4 therebetween, wherein said second solder bumps have at
- 5 least a portion that melts at a substantially lower
- 6 temperature than said first solder bumps.
- 1 2. A structure as recited in claim 1, wherein said
- 2 second solder bumps are larger than said first solder bumps.
- 1 3. A structure as recited in claim 1, wherein said
- 2 second solder bumps comprise a portion having a higher
- 3 concentration of tin than does said first solder bumps.
- 1 4. A structure as recited in claim 3, wherein said
- 2 portion comprises a eutectic concentration of tin.
- 1 5. A structure as recited in claim 3, wherein said
- 2 portion is adjacent to said second substrate.
- 1 6. A structure as recited in claim 3, wherein said
- 2 portion is centrally located within said second solder bump.
- 1 7. A structure as recited in claim 3, wherein said
- 2 portion is said entire second solder bumps.

1 8. A structure as recited in claim 1, wherein said
2 second solder bumps are for aligning said first substrate
3 and said second substrate before melting said first solder
4 bumps.

1 9. A structure as recited in claim 8, wherein said
2 second solder bumps are larger than said first solder bumps.

1 10. A structure as recited in claim 1, wherein said
2 second solder bumps melt at a temperature at least 25C less
3 than said first solder bumps.

1 11. A structure as recited in claim 1, wherein said
2 first substrate comprises a first semiconductor chip.

1 12. A structure as recited in claim 11, wherein said
2 second substrate comprises a second semiconductor chip.

1 13. A structure as recited in claim 12, wherein said
2 second chip is larger than said first chip.

1 14. A structure as recited in claim 12, wherein said
2 second chip further comprises wire bond pads for bonding to
3 a printed circuit board.

1 15. A method of joining, comprising:

2 (a) providing a first substrate and a second
3 substrate; and

4 (b) providing first solder bumps and second
5 solder bumps connecting said first substrate
6 and said second substrate, wherein said
7 second solder bumps have at least a portion
8 that melts at a substantially lower
9 temperature than said first solder bumps.

1 16. A method as recited in claim 15, wherein said
2 providing (b) comprises providing said second solder bumps
3 larger than said first solder bumps.

1 17. A method as recited in claim 15, wherein said
2 providing (b) comprises providing said second solder bumps
3 with a portion having a higher concentration of tin than
4 said first solder bumps.

1 18. A method as recited in claim 17, wherein said
2 portion comprises a eutectic concentration of tin.

1 19. A method as recited in claim 17, wherein said
2 providing (a) comprises providing said first substrate with
3 identical solder bumps at all positions and providing said
4 second substrate with solder bumps comprising a higher
5 concentration of tin at locations of said second solder
6 bumps than at locations of said first solder bumps.

1 20. A method as recited in claim 20, wherein said
2 providing (a) comprises providing said second substrate with
3 solder bumps consisting exclusively of tin exclusively at
4 locations of said second solder bumps.

1 21. A method as recited in claim 15, wherein said
2 first and said second solder bumps provide mechanical
3 connection between said first substrate and said second
4 substrate.

1 22. A method as recited in claim 20, wherein said
2 first solder bumps provide electrical connection between
3 said first substrate and said second substrate.

